



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): BIELLAK, STEVE; STOKOWSKI, STANLEY E.; VAEZ-IRAVANI, MEHDI
Assignee: KLA-TENCOR TECHNOLOGIES CORPORATION
Title: SYSTEM AND METHODS FOR A WAFER INSPECTION SYSTEM USING MULTIPLE ANGLES AND MULTIPLE WAVELENGTH ILLUMINATION
Serial No.: ~~09/1891693~~ 09/1891693 Filing Date: June 26, 2001
Examiner: Hao Q. Pham Group Art Unit: 2877
Docket No.: M-10693 US

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PETITION FOR EXTENSION OF TIME

Dear Sir:

Applicants respectfully petitions for a three-month extension of time within which to respond to the January 24, 2002 outstanding Office Action, such extension allowing the undersigned until July 24, 2002 to respond.

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Please charge the amount of \$920.00 as set forth in the enclosed transmittal letter.

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Respectfully submitted,

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